



*Ifur*

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No.: 10/762,526                      Group Art Unit: 1763  
Filing Date: January 23, 2004                      Examiner: Jeffrie R. LUND  
Applicant: Chang Won CHOI et al.  
Title: WAFER EDGE ETCHING APPARATUS AND METHOD  
Attorney Docket: 2557-000177/US

---

Customer Service Window  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314  
**Mail Stop Amendment**

November 6, 2006

**AMENDMENT**

Sir:

In response to the Office Action mailed June 6, 2006, the due date having been extended two (2) months to November 6, 2006, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

**Amendments to the Claims** begin on page 2 of this Amendment.

**Remarks** begin on page 9 of this Amendment.

|                    | Claims remaining<br>after Amendment |   | Highest number<br>previously paid for |   | Present extra |
|--------------------|-------------------------------------|---|---------------------------------------|---|---------------|
| <b>Total</b>       | 44                                  | - | 44                                    | = | 0             |
| <b>Independent</b> | 6                                   | - | 6                                     | = | 0             |

11/07/2006 SZEWDIE1 00000113 10762526

01 FC:1252

450.00 OP